



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masaaki KURIHARA et al.

Group Art Unit: 1756

Application No.: 10/614,345

Examiner: J. RUGGLES

Filed: July 8, 2003

Docket No.: 123770

For: PHASE MASK FOR FORMING DIFFRACTION GRATING, METHOD OF
FABRICATING PHASE MASK AND METHOD OF FORMING DIFFRACTION
GRATING

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the November 30, 2006 Office Action, the shortened statutory period for
reply having been extended by the attached Petition for Extension of Time, please consider
the following:

Amendments to the Specification;

Amendments to the Claims as reflected in the listing of claims; and

Remarks.